

AMENDMENT UNDER 37 C.F.R. § 1.116
EXPEDITED PROCEDURE
GROUP 1765
PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q61045

Fumiyoshi ONO

Appln. No.: 09/672,776

Group Art Unit: 1765

Confirmation No.: 2256

Examiner: Kin Chan Chen

Filed: September 29, 2000

For: COMPOSITION FOR POLISHING METAL ON SEMICONDUCTOR WAFER AND
METHOD OF USING SAME

AMENDMENT UNDER 37 C.F.R. § 1.116

MAIL STOP AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

FILED
AUG 14 2003

Sir:

This Amendment is submitted in response to the Office Action dated May 15, 2003, in which the Examiner set a three-month period for response.

Review and reconsideration on the merits in view of the following remarks and amendment is respectfully requested.

Please amend the above-identified application as follows on the accompanying pages.